

INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Complete if Known	
				Application Number	10/517,491
				Filing Date	December 10, 2004
				First Named Inventor	KAULE
				Group Art Unit	2872
				Examiner Name	Lavarias
				Confirmation No.	5564
Sheet		of	3	Attorney Docket Number	2732-149

FOREIGN PATENT DOCUMENTS							
Examiner Initials*	Cite No. ¹	Foreign Patent Document			Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	T ⁶
		Office ³ Code	Number ⁴	Kind ⁵ (if known)			
/ACL/	3	WO	94/14621	A1	Gao Gesellschaft fur Automation und Organisation mbH	07-07-1994	AB
Examiner Signature	/Arnel C. Lavarias/				Date Considered	11/02/2009	

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹Unique citation designation number. ²See attached Kinds of U.S. Patent Documents. ³Enter Office that issued the document, by the two-letter code. ⁴For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. ⁶Applicant is to place a check mark here if English language translation is attached. AB indicates that only an English language abstract is attached.

INFORMATION DISCLOSURE STATEMENT BY APPLICANT				Complete if Known	
				Application Number	10/517,491
				Filing Date	December 10, 2004
				First Named Inventor	KAULE
				Group Art Unit	2872
				Examiner Name	Lavarias
				Confirmation No.	5564
Sheet		of	3	Attorney Docket Number	2732-149

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials*	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published	T ²
/ACL/	4	RAI-CHOUDHURY, P., "SPIE handbook of microlithography, micromachining and microfabrication", <i>Handbook of Microlithography, Section 2.5 Systems</i> , 16 pages, 1997	
Examiner Signature	/Arnel C. Lavarias/		Date Considered 11/02/2009

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.
¹Unique citation designation number. ²Applicant is to place a check mark here if English language Translation is attached.